



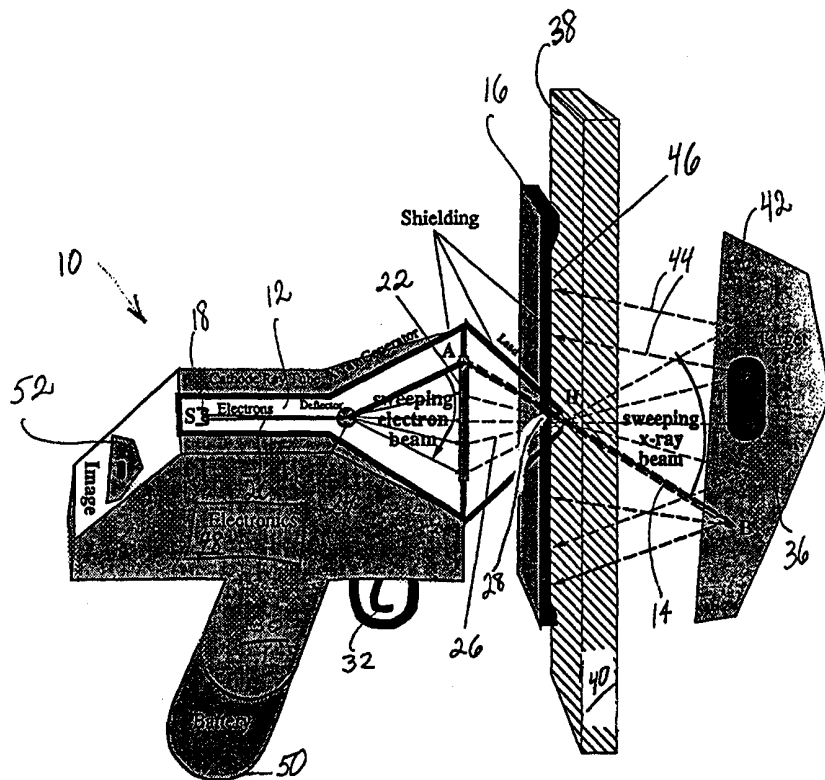
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(54) Title: UNILATERAL HAND-HELD X-RAY INSPECTION APPARATUS

(57) Abstract

A hand-holdable inspection device for three-dimensional inspection of a volume distal to a surface. The inspection device has a hand-holdable unit including a source of penetrating radiation for providing a beam of specified cross-section and a detector arrangement for detecting penetrating radiation from the beam scattered by the object in the direction of the detector arrangement and for generating a scattered radiation signal. Additionally, the inspection device has a controller for characterizing the volume based at least on the scattered radiation signal. The detector arrangement includes one or more backscatter detectors that may be disposed asymmetrically with respect to the beam and at differing displacements with respect to the surface.



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Unilateral Hand-Held X-Ray Inspection Apparatus

Technical Field

5 The present invention relates to an apparatus for imaging a concealed target by unilateral irradiation and detection of penetrating radiation.

Background of the Invention

Schulte (U.S. Patent no. 5,763,886) teaches a two-dimensional imaging backscatter probe for using a source of gamma-rays to illuminate a surface and for
10 generating a two-dimensional image of the backscattered radiation. It is valuable, in many applications, to know the shape and volumetric distribution as well as material characteristics of objects lying behind or beneath the illuminated surface. Schulte, however, fails to suggest that any depth or compositional information may be obtained with respect to objects lying behind or beneath the illuminated surface or to teach any
15 manner in which such information may be obtained. Additionally, Schulte requires that the probe be moved and that the position of the radiation detectors with respect to the target be sensed using means external to the probe in order to map the backscattered radiation.

Summary of the Invention

20 In accordance with one aspect of the invention, in one of its embodiments, there is provided a hand-holdable inspection device for three-dimensional inspection of a volume distal to a surface. The inspection device has a hand-holdable unit including a source of penetrating radiation for providing a beam of specified cross-section and a
25 detector arrangement for detecting penetrating radiation from the beam scattered by the object in the direction of the detector arrangement and for generating a scattered radiation signal. Additionally, the inspection device has a controller for characterizing the volume based at least on the scattered radiation signal.

30 In accordance with alternate embodiments of the invention, the source of penetrating radiation may be an x-ray source, the source may include a scanner, such as an electronic scanner, for scanning a direction of emission of the beam, the detector arrangement may be integral to the hand-holdable unit and may include an array of

semiconductor detectors, and the inspection device may additionally have a display screen for displaying an image characterizing the volume distal to the surface.

Brief Description of the Drawings

5 The foregoing features of the invention will be more readily understood by reference to the following detailed description taken with the accompanying drawings:

FIG. 1 provides a side view of an inspection system employing a hand-held source, detector, and display of penetrating radiation in accordance with a preferred embodiment of the present invention;

10 FIG. 2 is a side view of an inspection system employing a hand-held source and detector assembly, with an external display and control unit in accordance with an embodiment of the present invention;

FIG. 3a is a cross-sectional view of the inspection system of Fig. 1, employed in a "Probe" mode, in accordance with an embodiment of the present invention;

15 FIG. 3b is a cross-sectional view of a further embodiment of an inspection system, employed in a "Probe" mode, wherein extended backscatter detectors are employed;

FIG. 4a provides a schematic representation of an x-ray system employing backscatter detectors asymmetrically disposed with respect to an illuminating beam in accordance with a preferred embodiment of the present invention;

20 FIG. 4b provides a schematic representation of an x-ray system employing backscatter detectors asymmetrically disposed with respect to an illuminating beam in accordance with a further embodiment of the present invention; and

FIG. 5 is a cross-sectional view of an embodiment of an inspection system, employed in an "Image" mode, wherein the direction of the incident x-ray beam is scanned with respect to a detector arrangement fixed with respect to a beam-forming snout associated with the x-ray source.

Detailed Description of Preferred Embodiments

30 Fig. 1 shows a side view of the elements of an x-ray inspection device, designated generally by numeral 10. A source 12 emits penetrating radiation in a beam 14. Beam 14 of penetrating radiation, may be, for example, a beam of x-rays such as a polychromatic x-ray beam. The cross-sectional shape of beam 14 may be determined by

the geometry of source **12** and a collimating arrangement such as an aperture **28** provided in shielding **16**. Source **12** of penetrating radiation is preferably an cathode ray tube x-ray generator with a sweeping electron beam, as shown. Electron gun **18** emits an electron beam **20** that is accelerated toward anode **22** by virtue of the large positive
5 electrical potential applied to anode **22** with respect to electron gun **18** as well known in the art of x-ray generation. Since electrons comprising electron beam **20** bear electrical charge, their path may be modified by electrical or magnetic deflector means well known in the art. A deflector (otherwise referred to herein also as a "steerer") **24** employing one or both of electrical or magnetic deflector means is disposed along the path of electron
10 beam **20** between electron gun **18** and anode **20**. By application of an electrical potential or magnetic field to deflector **24**, electron beam **20** may be scanned across anode **22** in a controlled manner such as a raster scanning pattern. X-rays are generated as electron beam **20** impinges upon anode **20**. The emitted x-rays **26** are coupled through aperture **28** in shielding **16** such that, as electron beam **20** is scanned across anode **22**, the
15 orientation of the emergent x-ray beam **14** is swept correspondingly. A high-voltage potential and electron beam control potentials may be derived using on-board power supplies and a local battery **50**.

X-ray inspection device **10** may readily be held by an operator who can grip handle **30** and activate the emission of x-ray beam **14** by operation of trigger **32**. The x-
20 ray inspection device is advantageously employed for detecting the presence of an object **36** or cavity or other anomaly in a region posterior to the front surface **38** of a wall **40**, under circumstances where only front surface **38** is accessible to the operator. Inspection of the surface and of the volume disposed distally to the surface may thus be accomplished with only unilateral access to wall **40**. Additionally, object **36** may be
25 imaged, as described below.

X-rays **14** impinging on object **36** and on surrounding medium **42** are scattered by the respective matter through the process of Compton scattering. Backscattered radiation is designated by dashed rays labeled **44**. Scattered radiation is detected by one or more backscatter detectors (not shown) which constitute detector arrangement **46**
30 disposed on device **10** on the side of shielding **16** facing outward from the device and toward the object or surface undergoing inspection. In a preferred embodiment of the invention, detector arrangement **46** is an array of x-ray detectors arranged in a planar configuration. Within the scope of the invention, any x-ray detection technology known

in the art may be employed for scatter detector arrangement **46**. The detectors may be segmented scintillators or other solid state detectors, for example, or photomultipliers or liquid scintillators which may be doped with tin or other metal. The use of cesium-iodine on PIN diodes and of room-temperature CdZnTe semiconductors are examples of detector technologies which may be employed. Energy resolution of detector arrangement **46** is within the scope of the present invention and advantageously allows a determination of material characteristics of the object according to algorithms well-known in the art.

Output signals from the scatter detectors are transmitted to a processor **48**, and processed to obtain images of object **36** and its surrounding medium **42**, or to obtain other characteristics such, for example, as mass, mass density, mass distribution, mean atomic number, or likelihood of containing targeted threat material, all as known to persons skilled in the art of x-ray inspection. The distribution of detected radiation as beam **14** is swept in orientation allows a two-dimensional image of the concealed volume to be obtained. The term "image" refers to a mapping of raw or processed detector signals to positions in the plane, and may be stored in an internal or external memory, or, alternatively, may be displayed visually on a display **52** such as a video monitor.

Referring now to Fig. 2, portions of x-ray inspection system **10** may be separated from hand-held unit **54** and may be included in base unit **56** connected to hand-held unit **54** via cable **58** or via any other appropriate means of communication with hand-held unit **54**. Base unit **56** may contain, for example, a controller **60** for processing the signals provided by detector assembly **16** and/or battery supply **50** and power conditioning electronics **62** to provide power for electron gun filament **18** of source **12** and the electrical potentials applied to control steerer **24** and anode **22**. Additionally, base unit **56** may contain display **52** for displaying an image of target **36** posterior to wall **40**. An ambient radiation monitor **64** may be provided, in accordance with a preferred embodiment of the invention, so that x-ray beam intensity may be regulated to provide for safe operation of the unit. The use of ambient radiation monitors in the context of x-ray inspection equipment is described in detail in a co-pending U.S. patent application filed December 1, 1998.

Various modes of operation of x-ray inspection system **10** are described with reference to Figs. 3a-b and 4, wherein like numerals designate identical or similar

structural elements of the system. More particularly, operation in a "Probe" mode is described first with reference to Fig. 3a. In the Probe mode, electron beam **20** is maintained in a substantially fixed orientation relative to anode **22** such that, from among x-rays **78** generated at anode **22**, x-ray beam **14** is emitted through beam forming snout **66** in a substantially forward direction toward, and incident normally upon, wall **40**. Scattered x-ray radiation **44** from object **36** is detected by backscatter detectors **68**. Shielding **70** may be provided to discriminate against radiation **72** scattered by any source near to the inspection apparatus, such as in the wall facing itself. Further shielding **74** may be provided to protect personnel from scattered radiation.

Any method of determining the absolute or relative position in space of hand-held unit **10** in order to infer the position behind wall **40** of target **36** is within the scope of the present invention. As examples, and without limitation, optical or other electromagnetic locators **76**, or acoustic locators, may be employed to allow mapping via triangulation of the position of unit **10** and thereby to image and/or display backscatter signals vs. position.

In accordance with another embodiment of "Probe" mode operation, backscatter detectors **68** and **80** may be displaced in a direction either tangential to or perpendicular to wall **40**, either symmetrically with respect to beam **14** or asymmetrically. By separately processing the backscatter signals derived respectively at distinct laterally displaced backscatter detectors, the depth of object **36** may be determined in accordance with the detailed teachings of copending U.S. Provisional Patent Application 60/113,412, filed December 22, 1998, and entitled "Separate Lateral Processing of Backscatter Signals."

Referring now to Fig. 4a, the position and relative sizes of backscatter detectors **68** and **80** may be chosen, in accordance with preferred embodiments of the invention, to optimize the efficiency of the system in discriminating among x-rays scattered from various selected regions of the space penetrated by beam **14**, and to obtain images that enhance scattering features located at different depths behind wall **30**. Comparison of the scattered radiation flux detected at detectors **68** and **80** disposed with lateral asymmetry with respect to beam **14** may advantageously provide a quantitative measure of the distance from the plane of the detectors to scattering object **36** making reasonable assumptions regarding the isotropy of any medium ambient to object **36** through which

scattered radiation **140** and **142** propagates to the respective detectors. Scattered radiation **144** scattered from a nearby scattering source **112** may be shielded from detection by one or more of the backscatter detectors **68** and **80**.

As shown in Fig. 4a, backscatter detectors **68** and **80** are disposed asymmetrically with respect to beam **14**. Detector **68** subtends an angle, in the plane shown, of 6.1° with respect to object **36**, whereas detector **80** subtends an angle, in the plane shown, of 5.2° with respect to object **36**. The further detector **80** gets a fraction less than 1 of the counts recorded by near counter **3**. The ratio of counts detected by the respective counters approaches unity as the distance to object **36** increases (as measured with respect to the separation between detectors **68** and **80**). In this discussion, it is assumed, for simplicity, that propagation effects with respect to scattered beams **140** and **142** may be neglected. Knowledge of the orientation of beam **14** may allow the location of object **36** to be derived using straightforward algorithms.

An embodiment of source **10** of beam **14** of penetrating radiation is shown. Beam **20** of electrons emitted by cathode **18** is accelerated toward anode **22**. Electron beam **20** may be scanned with respect to anode **22** such that the orientation of beam **14** may be varied.

Referring now to Fig. 4b, an alternate embodiment of the invention is depicted in which backscatter detectors **68** and **80** are disposed at different distances with respect to concealing surface **30**. As discussed with reference to Fig. 4a, the difference in counts received by detectors **68** and **80** may be used to determine the distance between concealing surface **30** and scattering object **36**. Again, the ratio of scatter flux detected by the respective detectors approaches unity as the distance to scattering object **36** increases.

Fig. 5 depicts operation of x-ray inspection device **10** in an "Image" mode. In this mode, electron beam **20** is swept by deflector **24** across anode **22**, such as between positions **A** and **B**, indicated for illustrative purposes only. The resultant x-ray beam **14** emitted through beam forming snout **66** is thus scanned as well, impinging at different time intervals on object **A'** and object **B'**. Since the orientation of the beam **14** is known at each instant, a map may be derived of the orientation of scattering objects **A'** and **B'**. Additionally, since multiple backscatter detectors **68** and **80** are employed, tomographic information may also be derived and the position in space of the scattering objects may be inferred and displayed.

The described embodiments of the invention are intended to be merely exemplary and numerous variations and modifications will be apparent to those skilled in the art. All such variations and modifications are intended to be within the scope of the present invention as defined in the appended claims.

I CLAIM:

1. An inspection device for three-dimensional inspection of a volume distal to a surface, the device comprising:
 - a. a hand-holdable unit including a source of penetrating radiation for providing
5 a beam of specified cross-section;
 - b. a detector arrangement for detecting penetrating radiation from the beam scattered by the object in the direction of the detector arrangement and for generating a scattered radiation signal; and
 - c. a controller for three-dimensional characterization of the volume based at least
10 on the scattered radiation signal
such that three-dimensional characterization is performed without motion of the hand-holdable unit.
2. An inspection device according to claim 1, further comprising:
 - d. a display screen for displaying an image characterizing the volume distal
15 to the surface.
3. An inspection device according to claim 1, wherein the detector arrangement is integral to the hand-holdable unit.
4. An inspection device according to claim 2, wherein the display screen is integral to the hand-holdable unit.
- 20 5. An inspection device according to claim 1, further comprising an electromagnetic locator.
6. An inspection device according to claim 1, further comprising an acoustic locator.
7. An inspection device according to claim 1, wherein the source of penetrating
25 radiation includes a scanner for scanning a direction of emission of the beam.
8. An inspection device according to claim 1, wherein the source of penetrating radiation includes an electronic scanner for scanning a direction of emission of the beam.
9. An inspection system as set forth in claim 1, wherein the source of penetrating radiation is an x-ray source.
- 30 10. An inspection system as set forth in claim 1, wherein the detector arrangement includes an array of semiconductor detectors.
11. An inspection system as set forth in claim 1, wherein the detector arrangement includes at least two detectors asymmetrically disposed with respect to the beam.

12. An inspection system as set forth in claim 1, wherein the detector arrangement includes a first scatter detector disposed at a first displacement from the surface and a second detector disposed at a second displacement from the surface.
13. An inspection system as set forth in claim 12, wherein the first displacement is
5 unequal to the second displacement.
14. A method for inspecting a volume distal to a surface, the device comprising:
- a. illuminating the surface with penetrating radiation formed into a beam emitted by a hand-held unit;
 - b. detecting, with a detector arrangement, penetrating radiation scattered from
10 the volume; and
 - c. determining at least one characteristic of the volume based at least on the radiation scattered from the volume.
15. A method according to claim 14, further including the step of varying the orientation of the beam with respect to the surface.
- 15 16. A method according to claim 15, further including the step of displaying an image of the volume distal to the surface.

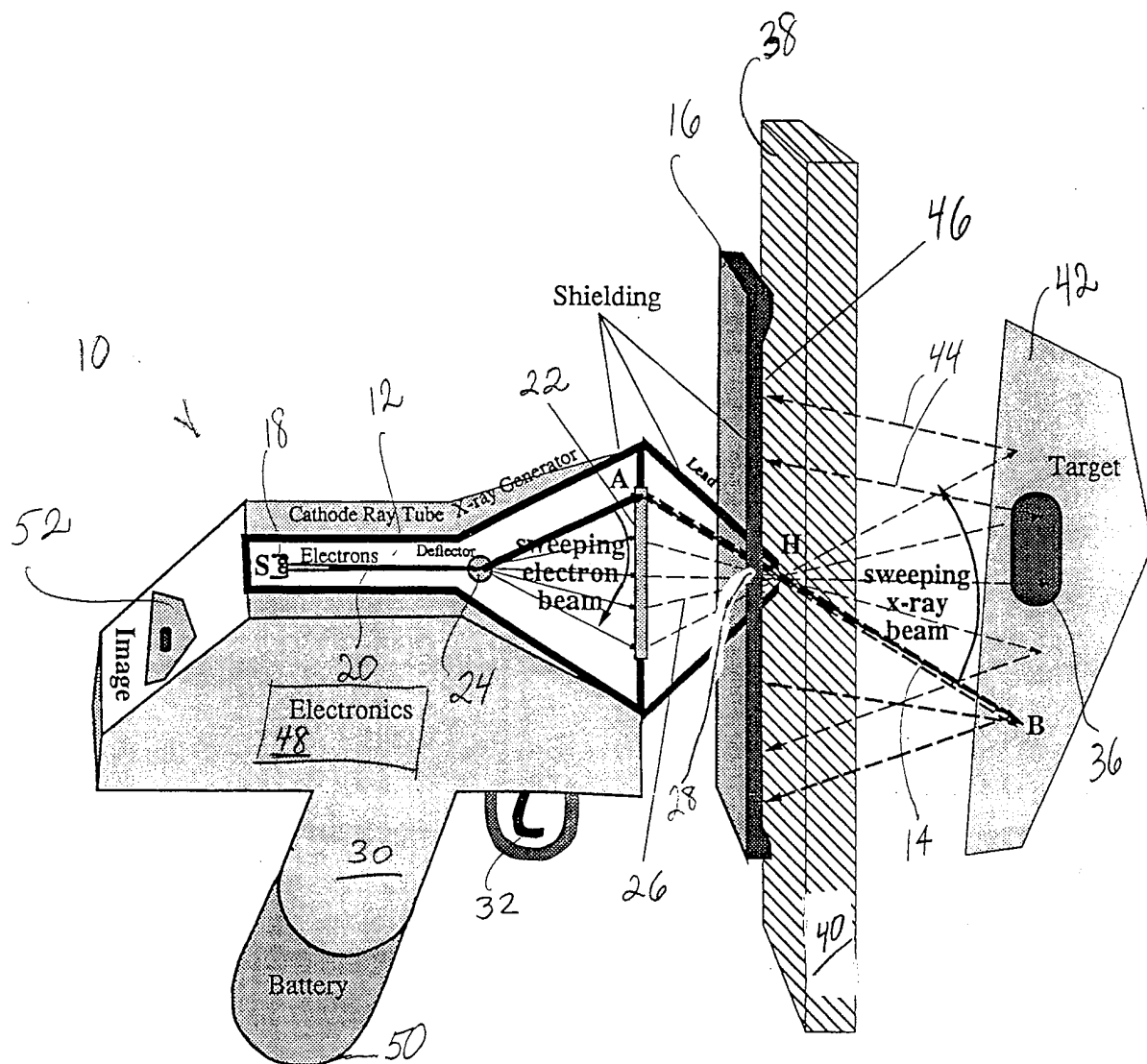


Figure 1

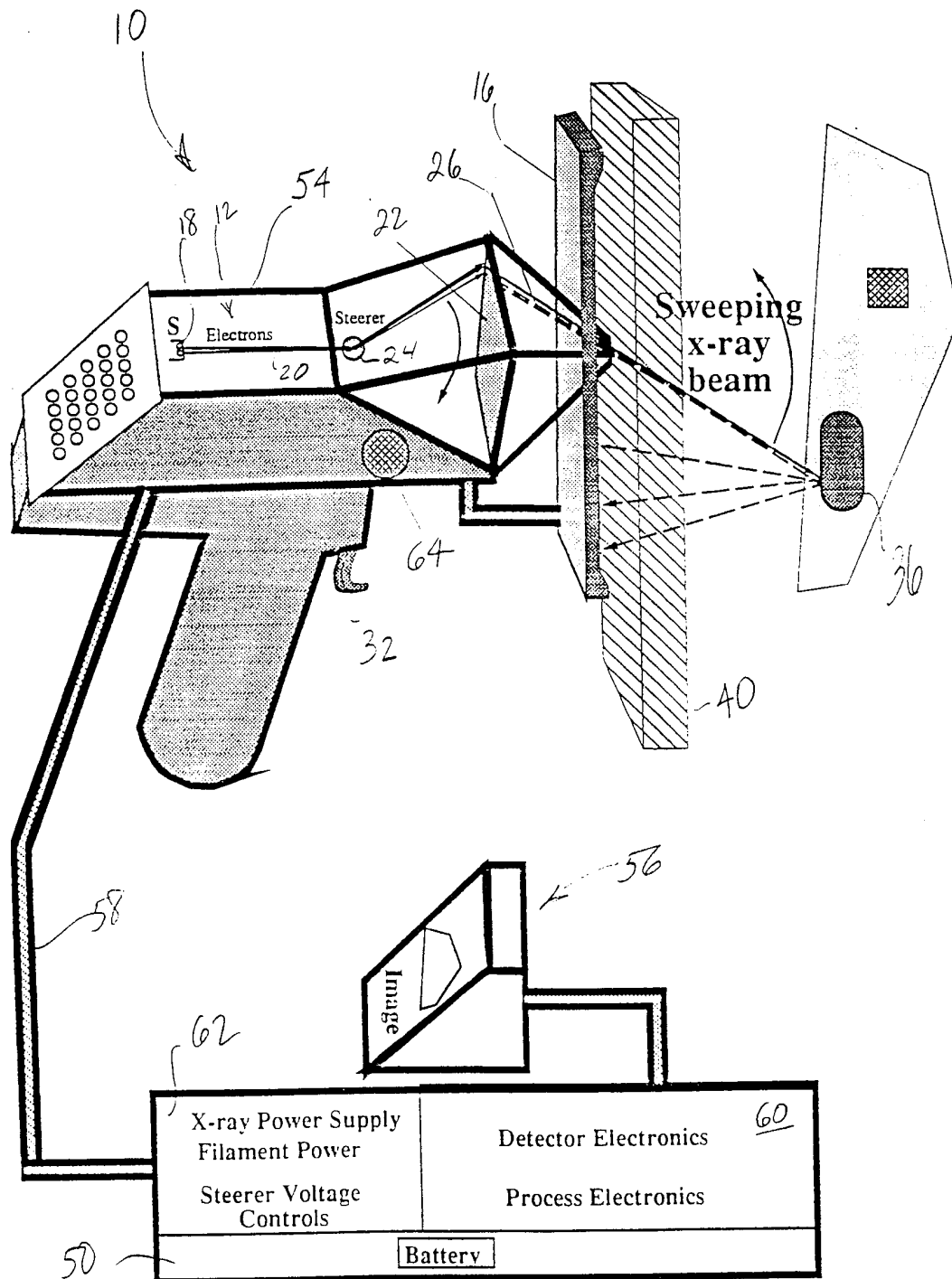
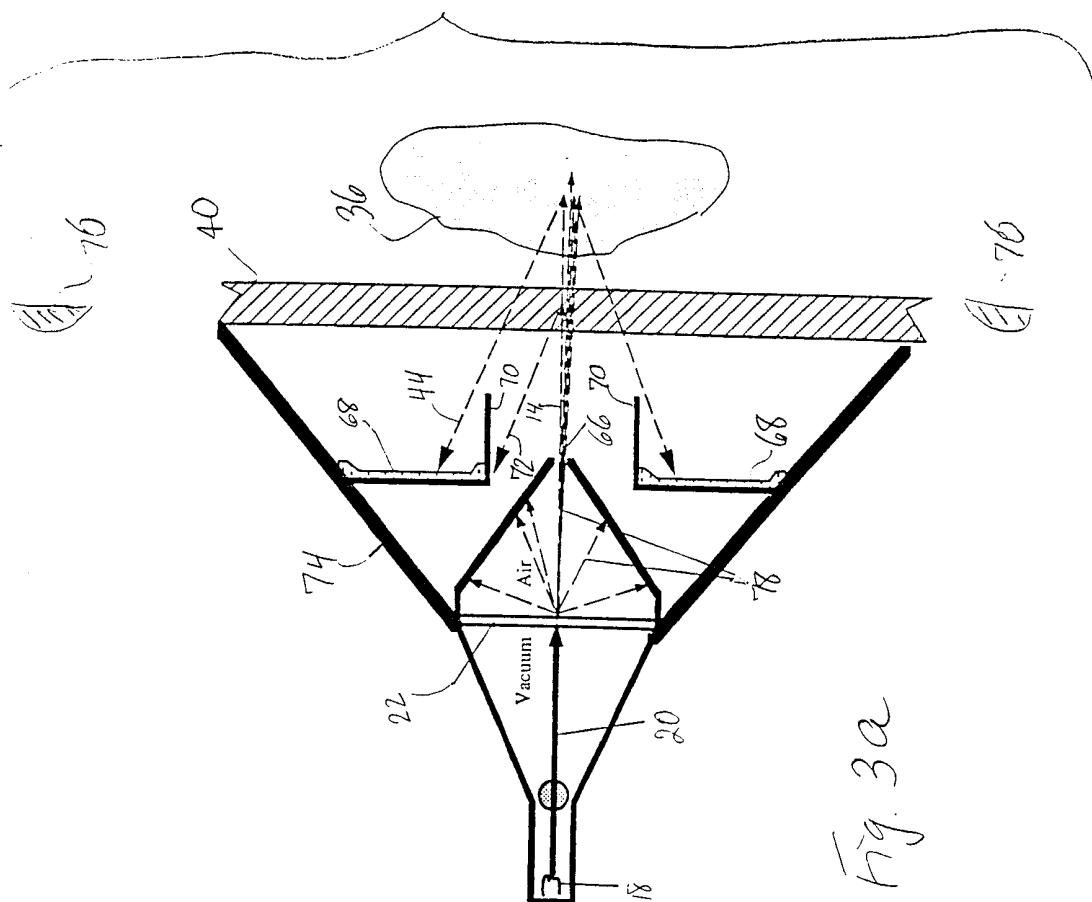


Fig 2



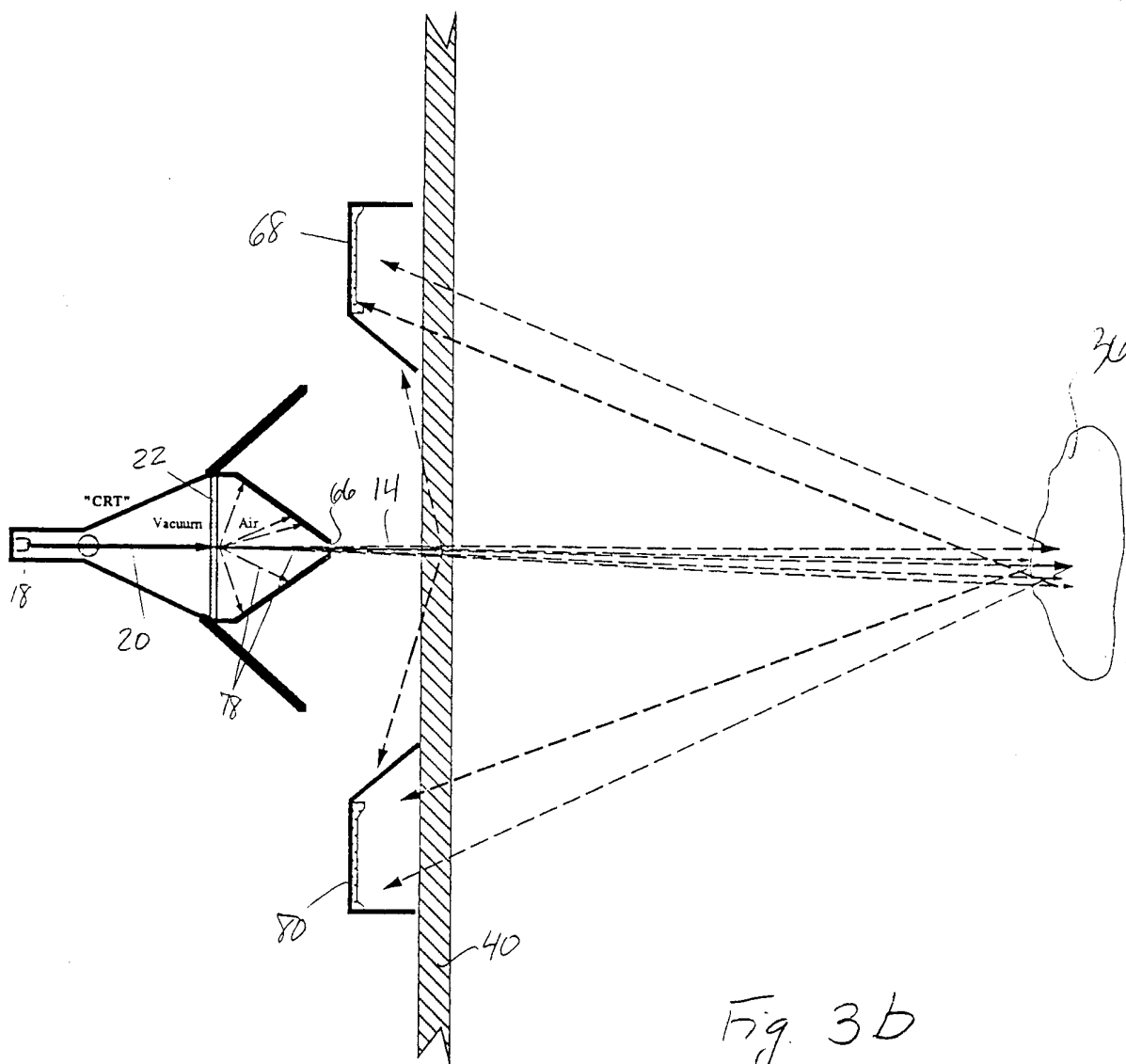
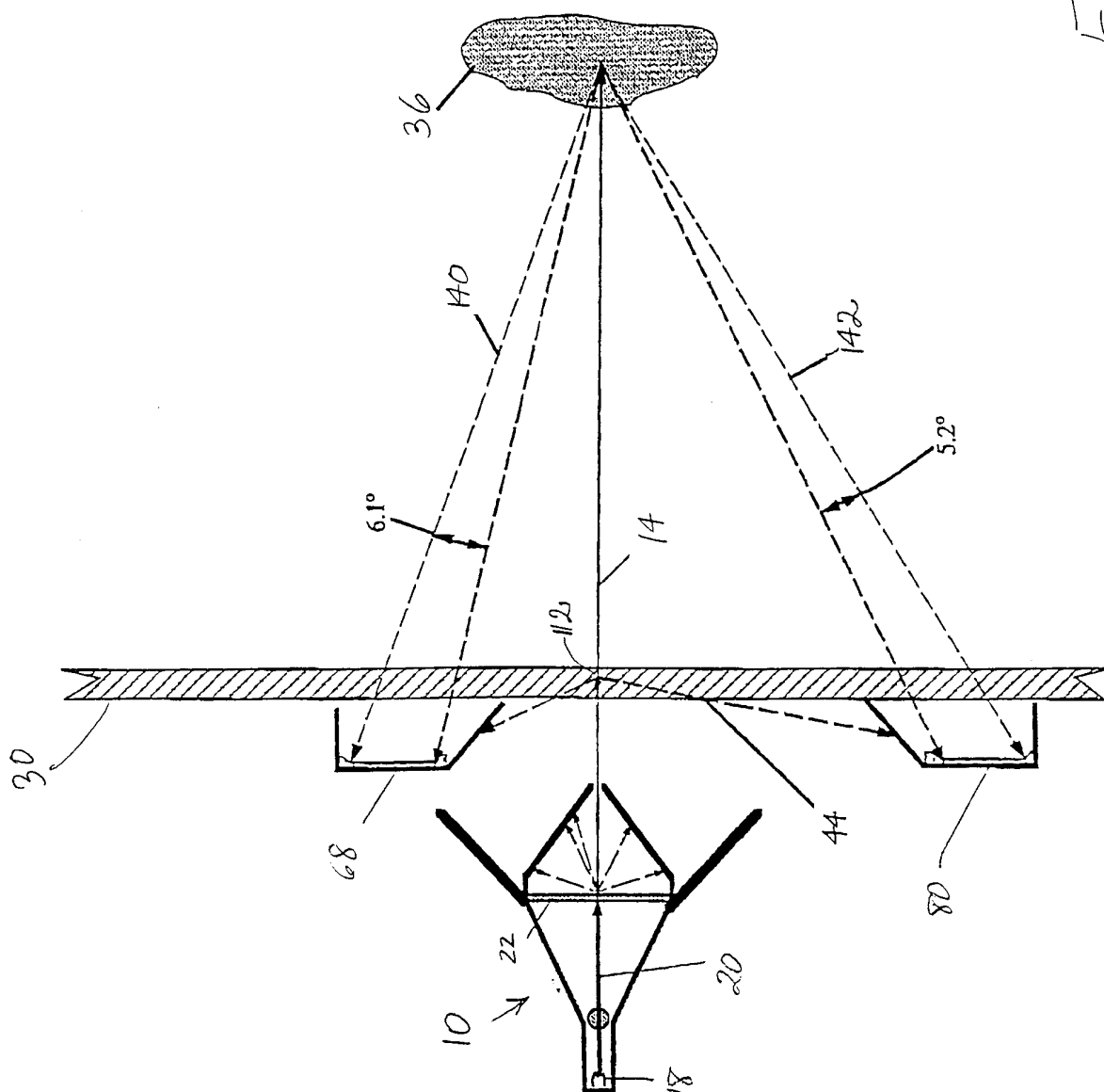


Fig. 3b

*Fig. 4a*

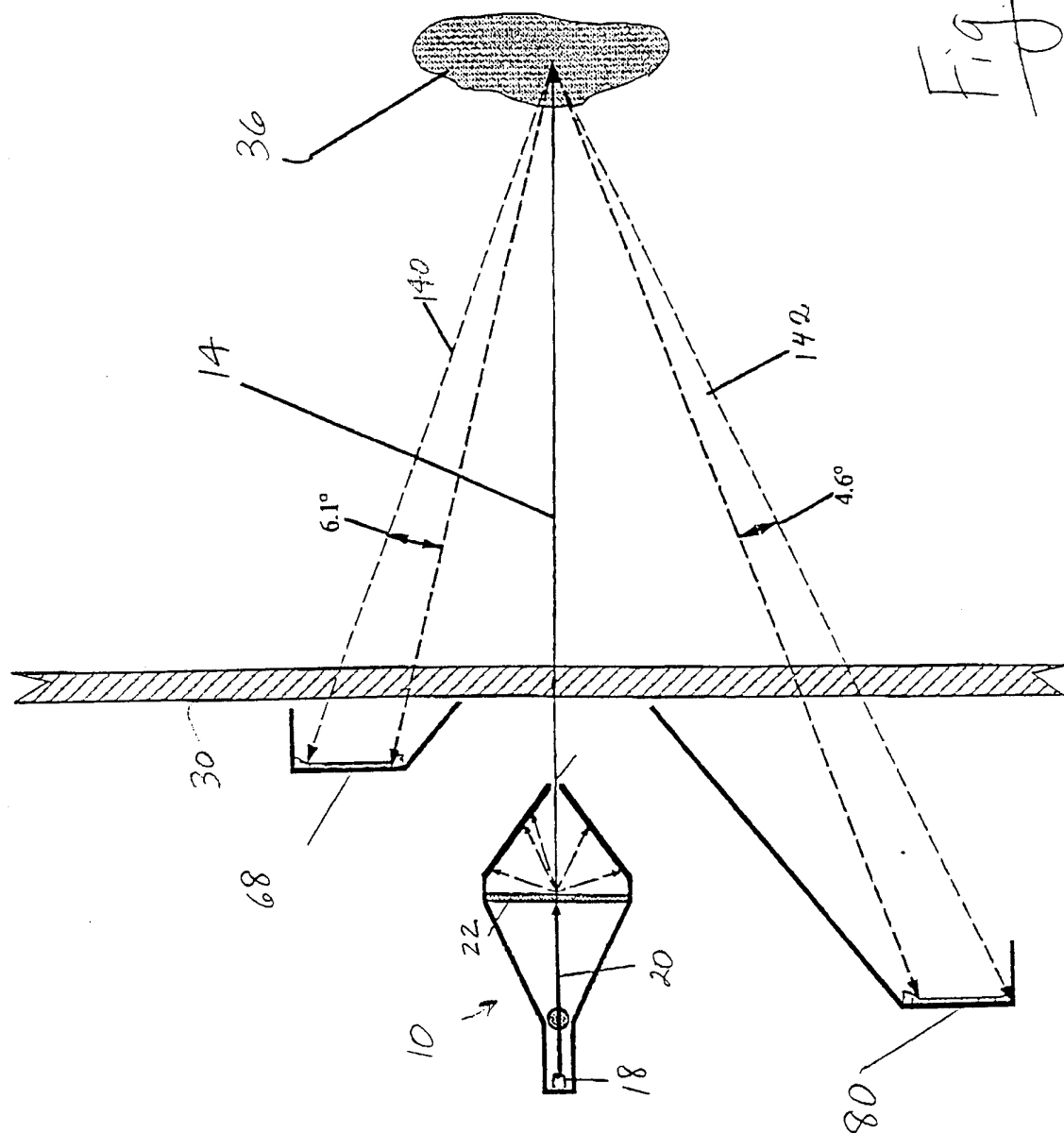


Fig 4b

